

Substrate Spinner EBS 11

The popular **Reinraumtechnik Lanz** spinner with new electronics.

This spinner is used for coating and developing ("puddle") of wafers and substrates. The optional built-in dispense arm allows for automated processing of single substrates, in conjunction with an optional dispense pump.

Description

User-friendly operation via touch panel. The program holds 60 recipes with 30 user-determined process cycles.

One process cycle consists of the following parameters:

Time:	0-999.9s
Speed:	0-10000 / min.
Acceleration/	0-80.000 rpm/sec.
Deceleration:	substrate depending

Output selection: 6 (basic system)

A standard vacuum chuck \varnothing 75mm is included. A variety of auto dispense options and customized chucks are available upon request.

Especially designed for laboratory and other low volume use, the EBS-11 can be flush-mounted or ordered as a stand-alone model.



Features and Benefits

- For wafers up to 200mm \varnothing
- Can also be used for substrates up to 5" square and .09" thick (Speed 6000 / min.) with special chucks
- Easy to use and program
- Vacuum and cover interlock (chuck stops revolving immediately)
- Fully digitalized speed setting and control without ADC and DAC
- Touch panel
- CE marking
- 12 months warranty

Facility Requirements

- Voltage/Power: 110V/230V / 50-60 Hz
- Vacuum: -0.8 bar, 5 l/min 4mm Ø connection
- Air Pressure: 4 bar, 0.5 l/min 4mm Ø
- Exhaust: -0.1 bar, 100 l/min 32mm Ø

Dimensions

- Base plate: w x d = 350mm x 440mm (aluminium) for in-deck mounting
- Height: 510mm (with exhaust and drain bottle 1.5 l) 280mm (without exhaust and drain bottle)
- Bowl: 225mm Ø (POM)
- Controller: w x h x d = 340mm x 135mm x 300mm
- Standard chuck size: 75mm Ø

Options

- Manual centering tool for up to 150mm wafers (recommended for non-centering chucks)
- Splash rings for up to 150mm wafers
- Chucks for special substrates and sizes
- EBR (edge-bead-removal) / BSR (back-side-rinse)
- Special materials (i.e. PVDF) for bowl and cover
- Stand-alone enclosure (w x d x h = 450mm x 550mm x 790mm)
- Pneumatic dispense arm (left-hand side at bowl)
- Pneumatic second dispense arm (right-hand side at bowl)
- Programmable dispense arm for up to 4 nozzles
- Dispense pump
- Dispense systems

Option: Coater

- Dispensing pump
- BSR EBR

Option: Developer

- Dispensing pump
- Fluid valves for DI water, developer, N₂
- Media tanks

